

862.C2032



PATENT APPLICATION

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
HIROSHI TSUJI ET AL.) : Examiner: NYA
Application No.: 09/691,234) : Group Art Unit: 2881
Filed: October 19, 2000) :
For: ELECTRON BEAM) :
LITHOGRAPHY APPARATUS) : January 17, 2001

Commissioner for Patents
Washington, D.C. 20231

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the document identified on the enclosed Form PTO-1449. A copy of the document is also enclosed.

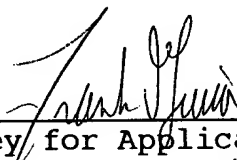
For the concise statement of relevance for the non-English document the Examiner is referred to the abstract attached thereto.

It is respectfully requested that the above information be considered by the Examiner and that a copy of

the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our below listed address.

Respectfully submitted,



Attorney for Applicants

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